

Applications

- Crystal annealing of ferroelectric thin films.
- Diffusion annealing, oxide film deposition annealing after ion implantation.
- Sintering, alloying treatment of Si and compound wafers.
- Glass substrate uniform temperature annealing.
- Thermal cycle, thermal shock, thermal fatigue testing.
- Temperature programmed desorption testing, catalytic effect testing.

Specifications

Best for research and development on small samples

The MILA-5000 series can perform high speed heating, high speed cooling, and clean heating, which are characteristics of the Infrared Gold Image Furnace. It can heat materials under adjustable atmospheres and combines a temperature controller and variable atmosphere chamber into a single low-cost infrared lamp heating system. Heating operations can be run by a PC connected via USB and data can be easily managed.

Features

- 50°C/s high speed heating.
- Select the desired atmosphere from vacuum, gas, gas flow, air.
- Precise temperature control.
- Compact, table-top design.
- Simple input of temperature recipe into computer connected with USB
- Display temperature data on the PC monitor during heating

Specifications			
Model	MILA-5000-P-N (high temperature type)	MILA-5000-P-F (uniform temperature type)	
Temperature Range	$ m RT \sim 1200~^\circ C$	$ m RT\sim 800~^\circ C$	*v
Sample Size	□ 20 × t 2 (mm)		*H
Atmosphere	Air, Vacuum, Gas flow		sa

 *Vacuum pumping system is optional.
 *Heating temperature changes according to the heated sample's infrared reflectance, absorption, heat capacity, and material.

Ultra-High Vacuum Mini Lamp Annealer MILA-5000UHV



Capable of supporting high vacuum with its compact design

Based on the MILA-5000-P-N (high temperature type), the MILA-5000UHV was born as a concept that supports an ultra-high vacuum and adds to MILA-5000 series features such as high speed heating and cooling, precise temperature control, clean heating, and flexible atmosphere selection. Heating operations can be run by a PC connected via USB and data can be easily managed.

Applications

- Heat treatment in an ultra-high vacuum.
- Temperature-programmed desorption gas analyzing furnace.

Features

- Heat treatment in an ultra-high vacuum atmosphere.
- Handles up to 10^{-5} Pa (when using TMP).
- Inherits the capabilities of the MILA-5000-P-N (high temperature type).
- Simple input of temperature recipe into computer connected with USB
- Display temperature data on the PC monitor during heating

Specifications

MILA-5000UHV		
RT \sim 1200 °C		
□ 20 ×t 2 (mm)		
Air, Vacuum, Inert gas		

*Vacuum pumping system is optional. *Heating temperature changes according to the heated sample's infrared reflectance, absorption, heat capacity, and material.

MILA-5050



ADVANCE RIKO A-5050

Applications

- Rapid thermal annealing of Si wafer and compound wafer
- Rapid thermal annealing of electronics material like substrates of optical CVD
- Heat treatment of glass substrates, ceramics and compound materials etc
- Thermal cycle test
- Thermal annealing of metal materials
- Heat resistance evaluation of coating films
- Heating and drying of organic materials and resins

• The Ps type has 40-mm wide reflective surfaces.

• The Pss type has 20-mm wide reflective surfaces

Lamp Number

1

that allow high density lamp configurations.

Both the Ps type and the Pss type can heat

a wide area by increasing the number of

Heat treatment up to 50 mm square size

This system is a new model of MILA-5000 Series, which has been valued by many customers. It is capable of heat treatment of up to 50mm square size samples and has been developed with still having a compact body.

Features

- Heat treatment up to the maximum 50 mm square size samples
- Maximum operating temperature 1200°C
- Desktop type in which heating furnace, chamber and temperature controller are all integrated
- Simple input of temperature recipe into computer connected with USB
- Display temperature data on the PC monitor during heating

Specifications

Temperature Range	RT \sim 1200 °C	
Heating rate	50 °C/s	
Sample Size	🗌 50 or φ 50 × t 2 (mm)	
Atmosphere	Vacuum, Gas flow	

*Vacuum pumping system is optional.

*Heating temperature changes according to the heated sample's infrared reflectance, absorption, heat capacity, and material.

Infrared Gold Image Furnace System **RHL-Ps / Pss series**

Useable in wide fields from carbon nanotube growth equipment to production equipment

The flat plate reflected infrared heating furnace can be used for applications such as a 2-inch to 300 mm diameter wafer lamp annealing system or a production baking furnace.

Features

Heating Length

(Light Emission length)

140 mm

265 mm

420 mm

140 mm

265 mm

420 mm

140 mm

200 mm

265 mm

420 mm

• Heating large glass substrates (Solar cells, FPD, etc.).

Input

1.2 kW

2 kW

3 kW

3.6 kW

6 kW

9 kW

3.6 kW

4.8 kW

6 kW

9 kW

- High-temperature, high-speed heating of semiconductor wafers.
- Annealing of thin steel sheets

Lamp Voltage

200 V

300 V

200 V

300 V

200 V

300 V

*1 Model number meaning For Ps(s)35V

P s(s) 3 5 V 1 2 3 4 5

- ① Paraboloidal surface type
- P : Parabolodial reflection ② Width of reflecting surface
- s : 40mm-width
 - ss: 20mm-width
- ③ Lamp number
- (4) Lamp length
- (5) Planar Heating type

heating Pss35V Pss38V

Heating Method

Planar

radiation

Applications

reflective surfaces.

Specifications

Model *1

Ps15V

Ps110V

Ps116V

Ps35V

Ps310V

Ps316V

Pss310V

Pss316V

· Please be aware that heating furnaces require cooling water

Heating temperature changes according to the heated sample's infrared reflectance, absorption, heat capacity, and material. · For other specification requirements, please feel free to contact us.